

# Updated Strategy and Scope of Metrology

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Our journal ‘*Metrology*’ has been up and running for a few years now, with interesting and ground-breaking publications covering the wide field that the concept of ‘metrology’ encompasses. Now, the time has come to contemplate and look back to the publications and consider whether the subjects listed in the scope are still appropriate and up-to-date. Considering the published papers and the developments in the various research fields, we concluded that the subjects mentioned in the scope are largely appropriate and up-to-date, but some fine adjustments and extensions can be made.

The basic scope is considered appropriate, but the listed topics have been updated and broadened as indicated in Table 1:

**Table 1.** Present scope and the updated version.

Present Scope	Updated Scope
<ul style="list-style-type: none"> <li>Traceability to SI units of complex measurement systems;</li> <li>Uncertainty evaluation;</li> <li>Micro- and nanosystems;</li> <li>Considerations on the fundamentals of measurement;</li> <li>Error separation methods;</li> <li>Novel methods inspired by the redefinition of the SI;</li> <li>Cyberphysical systems;</li> <li>Artificial intelligence, especially its effect on traceability;</li> <li>Machine learning for metrology;</li> <li>Digital twins;</li> <li>Metrology for sustainable manufacturing;</li> <li>Measurement uncertainty in dynamic processes.</li> </ul>	<ul style="list-style-type: none"> <li>Traceability to SI units of complex measurement systems;</li> <li>Measurement theory in a broad context;</li> <li>Measurement uncertainty and uncertainty evaluation;</li> <li>Considerations on the fundamentals of measurement;</li> <li>Error separation methods;</li> <li>Novel methods inspired by the redefinition of the SI;</li> <li>Cyberphysical systems;</li> <li>Artificial intelligence, especially its effect on traceability;</li> <li>Machine learning for metrology;</li> <li>Precision measurement;</li> <li>Digital twins;</li> <li>Metrology for sustainable manufacturing;</li> <li>Precision manufacturing;</li> <li>Measurement techniques and devices;</li> <li>Interferometry;</li> <li>XCT measurements;</li> <li>3D metrology;</li> <li>Frequency metrology;</li> <li>Surface metrology;</li> <li>Biomedical measurement;</li> <li>Virtual measurement;</li> <li>Power measurement.</li> </ul>



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With this update, we want to encourage the submission papers in the mentioned fields and continue the progress of the journal in the right direction.

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